

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Atty. Docket: 82821

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application )  
Applicant: Nakamura et al. )  
Serial No.: 09/856,212 )  
Filed: May 18, 2002 )  
For: PRODUCTION METHOD FOR SILICON )  
SINGLE CRYSTAL WAFER )

POWER TO INSPECT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313

Dear Sirs:

Please permit any one of the following individuals to inspect the above-identified U.S. Patent Application, to make copies of any papers that they may desire and to inspect and make copies of any and all assignments recorded with respect to the above-identified U.S. Patent Application.

J. Stuart Talbart  
Fred Taylor  
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Respectfully submitted,



Gerald T. Shekleton  
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Dated: August 5, 2003

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